

PROCEEDINGS OF SPIE

Optical Manufacturing and Testing VII

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Oliver W. Faehnle
Ray Williamson**
Editors

**28–29 August 2007
San Diego, California, USA**

Sponsored and Published by
SPIE

Volume 6671

Proceedings of SPIE, 0277-786X, v. 6671

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Author(s), "Title of Paper," in *Optical Manufacturing and Testing VII*, edited by James H. Burge, Oliver W. Faehnle, Ray Williamson, Proceedings of SPIE Vol. 6671 (SPIE, Bellingham, WA, 2007) Article CID Number.

ISSN 0277-786X

ISBN 9780819468192

Published by

SPIE

P.O. Box 10, Bellingham, Washington 98227-0010 USA

Telephone +1 360 676 3290 (Pacific Time) • Fax +1 360 647 1445

SPIE.org

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Printed in the United States of America.

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